

Docket No.: 21776-00052-US1  
(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

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In re Patent Application of:  
Nobuhiro Miki, et al.

Application No.: To be assigned  
(Div. of 09/636,821)

Group Art Unit: To be assigned

Filed: Concurrently Herewith

Examiner: To be assigned

For: RESIST FILM REMOVAL APPARATUS AND  
RESIST FILM REMOVAL METHOD

**FIRST PRELIMINARY AMENDMENT**

MS Non-Fee Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

**INTRODUCTORY COMMENTS**

Prior to examination on the merits, please amend the above-identified U.S. patent application as follows:

**IN THE SPECIFICATION:**

Before paragraph 1, kindly insert:

--This application is a divisional of U.S. Patent Appl. No. 09/636,821, filed August 14, 2000; which is a continuation-in-part of co-pending U.S. Patent Appl. No. 09/416,416, filed October 12, 1999--.